

b.) Amendments to the Claims:

Please cancel Claims 12 and 14-16 without prejudice or disclaimer of the subject matter therein. Please amend Claim 13 and add new Claims 17 and 18 as follows.

The status of all the claims is provided below.

1-12. (Cancelled).

13. (Currently amended) A plasma treatment apparatus comprising:

(i) a plurality of reactors each having an evacuable inside where at least one treatment substrate is set in, and having impedances different from each other;

(ii) a high-frequency power supply means for supplying high-frequency power into each reactor having been inside-evacuated, to cause glow discharge to take place in the reactor; and

(iii) a plurality of impedance regulation means provided correspondingly to the impedances of the reactors in order to regulate impedances on the side of each reactor and on the side of the high-frequency power supply means, wherein the high-frequency power supply means has an attachment part to which any one of the plurality of impedance regulation means is detachably mountable, and any one of the plurality of impedance regulation means is attached to the attachment part correspondingly to the impedances of the reactors.

14-16. (Cancelled).

17. (New) The plasma treatment apparatus according to Claim 13, wherein the substrate is a substrate for an electrophotographic light-receiving member.

18. (New) The plasma treatment apparatus according to Claim 13, wherein each of said reactors is mounted on a movable support stand.